



RESPONSE UNDER 37. C.F.R. § 1.116

EXPEDITED PROCEDUREEXAMINING GROUP 1762IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In Re Patent Application of:

Janardhanan Anand Subramony, et al.

Examiner: Meeks, Timothy H.

Application No.: 10/041,026

Art Unit: 1762

Filed: December 28, 2001

Confirmation No. 2626

For: METHOD FOR SILICON OXIDE AND
 OXYNITRIDE DEPOSITION USING
SINGLE WAFER LOW PRESSURE CVD

Commissioner for Patents

P.O. Box 1450

Alexandria, VA 22313-1450

AMENDMENT AND RESPONSE TO OFFICE ACTION

Dear Sir:

In response to the Final Office Action dated August 21, 2003, please enter this

Amendment and consider the following remarks.

FIRST CLASS CERTIFICATE OF MAILING

I hereby certify that this correspondence is being deposited with the United States Postal Service as first class mail with sufficient postage in an envelope addressed to the Commissioner for Patents, P.O. Box 1450 Alexandria, VA, 22313-1450

on September 26, 2003

Date of Deposit

Michelle Begay

Name of Person Mailing Correspondence

Michelle Begay
 Signature

September 26, 2003

Date